

Minibrate Top Furnace (nitrogen/oxygen anneal)

Overview

The Minibrate Top Furnace is an atmospheric horizontal quartz tube furnace used for annealing in nitrogen, oxygen, or a mixture thereof. This tube may also be used for thermal oxidation.

LMACS Name	Minibrate Top Furnace (nitrogen/oxygen anneal)
Confluence Label	thermco-minibrate-topfurnace
Process Area	ANCILLARY
Model	MB-81
Vendor	THERMCO
Team	Timothy Harrison Glenn Elashuk Aaron Hryciw

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System Features

Process Gases	- N₂ - O₂
Temperature Range	- Min: 450 °C (lower is possible with manual temperature control) - Max: 1050 °C

Documents

Operating Procedure	Minibrate Furnace SOP
Hazard Assessment	Minibrate Top/Middle Furnace HA

Related Documents

- J.A. Woollam VASE Ellipsometer (Equipment)
 - [equipment](#)
 - [characterization](#)
 - [requires-update](#)
 - [vase-ellipsometer](#)
 - [vase-vb-400](#)
 - [materials-analysis](#)
 - [vase](#)
- JA Woollam M-2000 Ellipsometer (Equipment)
 - [equipment](#)
 - [characterization](#)
 - [requires-update](#)
 - [vase-m2000-ellipsometer](#)
 - [materials-analysis](#)
- Angstrom Covap Thermal Evaporator III (Equipment)
 - [equipment](#)
 - [angstrom-covap-thermal-evaporator](#)
 - [deposition](#)
- AJA Orion 8 Sputtering System (Moe) (Equipment)
 - [equipment](#)
 - [aja](#)
 - [sputtering-system-moe](#)
 - [deposition](#)
- PDMS Process Area (Equipment)
 - [equipment](#)
 - [packaging](#)

- [AML - AWB-04 Wafer Aligner-Bonder \(Equipment\)](#)
 - equipment
 - aml-awb-04
 - awb-04
 - aml-awb-04-wafer-aligner-bonder
 - packaging
- [Using the Disco 3240 Blade Change Locker \(nanoFAB Knowledge Base\)](#)
 - interlock
 - how-to
 - disco-3240
 - blade-change
 - blade
 - standard-operating-procedure
 - equipment-configuration
 - packaging
 - equipment
- [nGauge AFM \(Equipment\)](#)
 - equipment
 - characterization
 - microscopy
 - afm
 - ngauge
- [Olympus LEXT OLS3100 Confocal Laser Scanning \(Equipment\)](#)
 - equipment
 - characterization
 - olympus-ols-laser
 - confocal
 - ols
 - lext
- [KJLC 150LX Atomic Layer Deposition \(Equipment\)](#)
 - equipment
 - requires-update
 - kjlc-150lx-ald
 - \$labeltext
 - deposition
- [Zeiss Versa Xradia 620 HA \(Equipment\)](#)
 - hazard-assessment
 - characterization
 - equipment
 - xrm
 - zeiss-xradia-620
- [Perkin-Elmer NIR-UV Spectrophotometer HA \(Equipment\)](#)
 - hazard-assessment
 - characterization
 - equipment
 - xrm
 - zeiss-xradia-620
- [KLA - Alpha-Step IQ Profilometer - Characterization HA \(Equipment\)](#)
 - hazard-assessment
 - characterization
 - equipment
 - xrm
 - zeiss-xradia-620
- [Disco DAD 3240 Dicing Saw \(Equipment\)](#)
 - equipment
 - dicing
 - disco-3240
 - packaging
 - disco-3240-dicing-saw
- [Disco DAD 3241 Dicing Saw \(Equipment\)](#)
 - equipment
 - dicing
 - packaging
 - disco-3241
 - disco-3241-dicing-saw